香港大學 機械工程系
Department of Mechanical Engineering
THE UNIVERSITY OF HONG KONG

SEMINAR

Title: Central Fabrication Laboratory- Technical sharing session –Analysis of Semiconductor Cleanliness and Detection Methods（Auto SEM，CT，CP，AFM）

Date: **22 April 2026 (Wednesday)**
Time: **9:30am - 11:00am**
Venue: **Room 7-35**
Haking Wong Building, HKU

Speaker: **Mr. Andy Liu**
Cleanness product manger
Phenom Scientific

Language: **Mandarin**

Limited seats available on a first-come first-served basis

Abstract:

The Central Fabrication Laboratory (CFL) is a cutting-edge cleanroom facility located at the University of Hong Kong. Its primary mission is to provide advanced fabrication facilities and expertise to enhance teaching and research activities in micro/nano fabrication. As a leading research laboratory, CFL offers open access not only to University of Hong Kong members but also to local and international institutions, researchers, and companies, with collaborations from the private sector always encouraged. The technical sharing sessions offered by CFL are designed to keep participants updated on the latest micro/nano fabrication techniques and provide valuable networking opportunities with experts from around the world.

As semiconductor manufacturing processes advance to more advanced nodes such as 3nm and 2nm, the control of microparticle contamination has become a critical factor determining product yield.

This seminar introduces automated particle detection methods based on the principles of SEM and dark-field imaging. It will also share applications of SEM, CP, CT and other technologies in the semiconductor field.

Biography:

Andy Liu graduated from Beihang University in 2016 with a Master's degree. He currently serves as a Product Manager in the Cleanliness Detection Business Unit (BU) at Phenom Scientific. With 6 years of professional experience, he specializes in cleanliness detection applications across automotive, lithium-ion battery, and semiconductor industrial sectors. Additionally, he has conducted research on the automation of scanning electron microscopes (SEM) as well as other detection methodologies.

ALL INTERESTED ARE WELCOME

For further information, please contact Mr. YIP P.S. (3910 2637, psanyip@hku.hk)
or Prof. Chan P.K.L. (3917 2634, pklc@hku.hk).